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INFORMATION DISCLOSURE CITATION PTO-1449		ATTY. DOCKET NO. P102-US		SERIAL NO. 10/627,155			
		APPLICANT Patel, et al					
		FILING DATE 7/24/03		GROUP Not Yet Assigned			
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
	2003/0160540	8/28/03	Miller, et al.				
	6,819,470	11/16/04	Meier, et al.				
	2003/0117688	6/26/03	Meier, et al.				
	2003/0117686	6/26/03	DiCarlo				
	2002/0093721	7/18/02	Knipe				
	6,724,518	4/20/04	Meyer, et al.				
	6,147,790	11/14/00	Meier, et al.				
	6,285,490	9/4/01	Meier, et al.				
	6,523,961	2/25/03	Ilkov, et al.				
	2002/0024641	2/28/02	Ilkov, et al.				
	2004/0004753	1/8/04	Pan				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	WO 2004/001487	12/13/03	PCT			<input type="checkbox"/>	<input type="checkbox"/>
	WO 2004/000720	12/13/03	PCT			<input type="checkbox"/>	<input type="checkbox"/>
	WO 2004/001717	12/13/03	PCT			<input type="checkbox"/>	<input type="checkbox"/>
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
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Attorney Docket No.: 38187-2594

Filed 2/15/05

SHEET 1 OF 1

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INFORMATION DISCLOSURE CITATION PTO-1449 SHEET 1 OF 1		ATTY. DOCKET NO.		SERIAL NO.			
		P102-US		10/627,155			
		APPLICANT Patel, et al					
FILING DATE 7/24/03		GROUP					
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
	5,835,256	11/10/98	Huibers				
	6,046,840	04/04/00	Huibers				
	6,529,310	03/04/03	Huibers, et al.				
	6,396,619	05/28/02	Huibers, et al.				
	6,523,961	02/25/03	Ilkov, et al.				
	2003/0054588	03/20/03	Patel, et al.				
	2004/0125346	07/01/04	Huibers				
	2002/0132389	09/19/02	Patel, et al.				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
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						<input type="checkbox"/>	<input type="checkbox"/>
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
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Attorney Docket No.: 38187-2594

PTO/SB/08A (10-01)

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet 1 of 6

Complete If Known

Application Number	10/627,155
Filing Date	7/24/03
First Named Inventor	Patel
Art Unit	Not Yet Assigned
Examiner Name	Not Yet Assigned
Attorney Docket Number	P102-US

U.S. PATENT DOCUMENTS

Examiner Initials	Cite No. ¹	Document Number Number - Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
	/	US- 3,511,727	05-12-1970	Haya, R.G.	
		US- 4,190,488	02-26-1980	Winters, H.F.	
		US- 4,310,380	12-12-1982	Flamm et al.	
		US- 4,498,953	02-12-1985	Cook et al.	
		US- 6,051,503	04-18-2000	Bhardwaj, J.K.	
		US- 6,436,229	08-20-2002	Tal et al.	
		US- 6,162,367	12-19-2000	Tal et al.	
		US- 6,290,884 B1	09-18-2001	Patel et al.	
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		US- 2001/0002663 A1	06-07-2001	Tal et al.	
		US- 5,439,553	08-08-1995	Grant et al.	
		US- 2002/0032229 A1	03-21-2002	Leboultz et al.	
		US- 2002/0198524 A1	12-25-2002	Hubars, et al.	
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		US- 2002/0165899	12-12-2002	Reid	
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		US- 5,835,256	11-10-1998	Hubars, A.	
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Examiner Initials	Cite No. ¹	Foreign Patent Document Country Code ³ - Number ⁴ - Kind Code ⁵ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		EP-0704884-A2	04-03-1996	Mehta, J.	
		EP-0822582-A2	02-04-1998	Bhardwaj, J.K.	
		EP-0822584-A2	04-04-1998	Bhardwaj, J.K.	
		WO-9949506	09-30-1999	McQuarrie, A.D.	
		EP-0878824-A2	11-18-1996	McQuarrie et al.	
		EP-0878824-A3	01-19-2000	McQuarrie et al.	
		JP-1982/57098679-A	06-18-1982	Tsunetschi, A.	
		JP-1983/58130529-A	08-04-1983	Yoshihiro et al.	
		JP-1985/60057938-A	04-03-1985	Katsumi et al.	
		WO-98/32163	07-23-1998	Tal et al.	

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Substitute for form 1449A/PTO				<i>Complete if Known:</i>	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Application Number	10/627,155
Sheet	2	of	6	Filing Date	7/24/03
				First Named Inventor	Patel
				Art Unit	Not Yet Assigned
				Examiner Name	Not Yet Assigned
				Attorney Docket Number	P102-US

U.S. PATENT DOCUMENTS					
Examiner Initials	Cite No. 1	Document Number Number- Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		US- 6,409,876 B1	06-25-2002	McQuarrie, et al.	
		US- 6,396,619 B1	05-28-2002	Huibers, et al.	
		US- 6,576,489 B2	08/10/03	Leung, et al.	
		US- 6,238,581	05-29-2001	Hawkins, et al.	
		US- 6,115,172	09-05-2000	Jeong	
		US- 6,204,080	03-20-2001	Hwang	
		US- 2003/0071015 A1	04/17/03	Chinn, et al.	
		US- 2002/0164879 A1	11/07/02	Leung, et al.	
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		US- 6,197,810 B1	03/06/2001	Teda	
		US- 6,500,358 B2	12/31/02	Goto, et al.	
		US- 2003/0124848 A1	07/03/03	Chinn, et al.	
		US- 2003/0219986 A1	11/27/03	Rattner, et al.	
		US-			

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Examiner Initials	Cite No. 1	Foreign Patent Document Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		JP-1997/09251981-A.	09-22-1997	Kazuaki et al.	
		JP-1998/10313128-A	11-24-1998	Hannin et al.	
		JP-1998/10317169-A	12-02-1998	McQuarrie et al.	
		JP-1986/51187238-A	08-20-1986	Nobuo et al.	
		JP-1986/81270830-A	12-01-1986	Toru, T.	
		JP-1987/82071217-A	04-01-1987	Toru et al.	
		JP-1988/83165713-A	08-28-1988	Tadashi, F.	
		JP-1988/81053732-A	03-17-1988	Arata et al.	
		JP-1986/81134019-A	08-21-1986	Shinji et al.	
		JP-1988/81181131-A	08-13-1986	Shinji et al.	

Examiner Signature	Date Considered
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¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 801.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

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Substitute for form 1449A/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/627,155
(use as many sheets as necessary)				Filing Date	7/24/03
				First Named Inventor	Patel
				Art Unit	Not Yet Assigned
				Examiner Name	Not Yet Assigned
Sheet	3	of	6	Attorney Docket Number	P102-US

U.S. PATENT DOCUMENTS

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STATEMENT BY APPLICANT**

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Sheet 4 of 6

Complete If Known

Application Number	10/627,155
Filing Date	7/24/03
First Named Inventor	Patel
Group Art Unit	Not Yet Assigned
Examiner Name	Not Yet Assigned
Attorney Docket Number	P102-US

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. 1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T2
		ALIEV et al., "Development of Si(100) Surface Roughness at the Initial Stage of Etching in F2 and XeF2 Gases Ellipsometric Study", Surface Science 442 (1999), pp. 206-214.	
		GLIDEMEISTER, J.M., "Xenon Difluoride Etching System" (Nov. 17, 1997).	
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		IBBOTSON et al., "Plasmaless Dry Etching of Silicon with Fluorine-containing Compounds", J. Appl. Phys. Vol. 56 No. 10 (Nov. 1984), pp. 2938-2942.	
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		WINTERS, H.F., "Etch Products from the Reaction of XeF2 with SiO2, Si3N4, SiC, and Si in the Presence of Ion Bombardment", J. Vac. Sci. Technol. B 1(4) (Oct/Dec 1983), pp. 927-931.	

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

5

of

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Complete If Known

Application Number	10/627,155
Filing Date	7/24/03
First Named Inventor	Patel
Group Art Unit	Not Yet Assigned
Examiner Name	Not Yet Assigned
Attorney Docket Number	P102-US

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

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		Kurt Willema, Etch Rates for Micromachining Processing-Part II, 2003 IEEE, Pgs 761-778, Journal of Microelectromechanical Systems, Vol. 12, No. 6, December 2003.	
		WINTERS et al., "The Etching of Silicon with XeF ₂ Vapor", Appl. Phys. Letter, Vol 34(1) (January 1, 1979), pp. 70-73.	
		XACTIX, Inc., Marketing Brochure (June 27, 1999).	
		"Xenon Difluoride Isotropic Etch System: Seeing Is Believing", Surface Technology Systems Ltd. brochure, Newport, UK (date unknown).	
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		BASSOM et al., "Modeling and Optimizing XeF ₂ -enhanced FIB Milling of Silicon", 25th International Symposium for Testing and Failure Analysis, Santa Clara, CA (Nov. 14 -18, 1999), pp. 255-261 (abstract only).	
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		CHANG et al., "Gas-Phase Silicon Micromachining with Silicon Difluoride", Proceedings of the SPIE - The International Society for Optical Engineering, Vol. 2841 (1995), pp. 117-128 (abstract only).	

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Date Considered

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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet

8

of

8

Complete If Known	
Application Number	10/627,155
Filing Date	7/24/03
First Named Inventor	Patal
Group Art Unit	Not Yet Assigned
Examiner Name	Not Yet Assigned
Attorney Docket Number	P102-US

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. 1	Include name of the author (In CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T2
		SEBEL et al., "Reaction Layer Dynamics in Ion-Assisted Si/XeF ₂ Etching: Temperature Dependence", J. Vac. Sci. Technol. A, Vac. Surf. Films, Vol. 18, No. 6, (Nov. 2000), pp. 2759-2769 (abstract only).	
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		SUGANO et al., "Study on XeF ₂ Pulse Etching Using Wagon Wheel Pattern", Proceedings of the 1999 International Symposium on Micromechanics and Human Science: Towards the New Century, Nagoya, Japan (Nov. 23 - 28, 1999), pp. 163-167 (abstract only).	
		WANG et al., "Gas-Phase Silicon Etching with Bromine Trifluoride", International Solid State Sensors and Actuators Conference (Transducers '97), Chicago, IL, Vol. 2 (June 16 - 19, 1997), pp. 1505-1508 (abstract only).	
		MUTHUKUMARAN et al., "Gas-Phase Xenon Difluoride Etching of Microsystems Fabricated Through the Metal-1.5-μm CMOS Process", Can. J. Electr. Comput. Eng. (Canada), Vol. 25, No. 1 (Jan. 2000), pp. 35-41 (abstract only).	
		TODA et al., "Thin Beam Bulk Micromachining Based on RIE and Xenon Difluoride Silicon Etching", International Solid State Sensors and Actuators Conference (Transducers '97), Chicago, IL, Vol. 1 (June 16 - 19, 1997), pp. 671-674.	
		SEBEL et al., "Etching of Si Through a Thick Condensed XeF ₂ Layer", J. Vac. Sci. Technol. A, Vac. Surf. Films, Vol 18, No. 5 (Sept/Oct 2000), pp. 2090-2097 (abstract only).	

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